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10/536696
PATENT

Docket No.: 4590-410

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Inventor(s): Arnaud GRISARD et al. : Confirmation No. 2283
U.S. Patent Application No. 10/536,696 :
Filed: May 27, 2005 :
For: METHOD OF PRODUCING THICK NON-LINEAR OPTICAL GRATINGS

INFORMATION DISCLOSURE STATEMENT


Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Respectfully submitted,
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INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 4590-410		U.S. PATENT APPLICATION NO. 10/536,696	
				APPLICANT Arnaud GRISARD et al.			
				FILING DATE May 27, 2005		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	5,349,466	09-20-1994	Delacourt , et al.				
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
	Christopher B. Ebert, Loren A. Eyres, Martin M. Fejer, James S. Harris, Jr. "MBE growth of antiphase GaAs films using GaAs/Ge/GaAs heteroepitaxy" Journal of Crystal Growth 201/202 (1888) 187-193						
EXAMINER				DATE CONSIDERED			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.